

Docket No.: 067161-0301

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	:Customer Number: 20277
	:
Toshihiko TANAKA	:Confirmation Number: Not yet assigned
	:
Application No.: Not yet assigned	:Group Art Unit: Not yet assigned
	:
Filed: October 03, 2005	:Examiner: Not yet assigned
	:
For: SEMICONDUCTOR DEVICE FABRICATION METHOD AND MASK PATTERN DATA GENERATION METHOD	

INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner for Patents and Trademarks
Washington, D. C. 20231

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached form PTO-1449. It is respectfully requested that the references be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed with the application and no certification or fee is required.

A copy of the foreign search report is attached for the Examiner's information. Please note this is a PCT application in the entry of the National Phase in the U.S. and copies of the references cited were transmitted by WIPO and are believed to be in the file of the above identified application and readily available to the Examiner. Therefore it is believed that Applicants have met all requirements regarding duty of disclosure under 37

Not yet assigned

JC12 Rec'd PCT/PTC 03 OCT 2005

CFR 1.56. Acknowledgement and consideration of these documents are respectfully requested.

A copy of the foreign search report is attached for the Examiner's information. Please note this is a PCT application in the entry of the National Phase in the U.S. However, to ensure that these references are available to the Examiner, we are providing copies of these references herewith. Since the Search Report was from the U.S. JPO or EPO search authorities, copies of these references should have been supplied to the USPTO under the trilateral agreement and are believed to be in the file of the above identified application and readily available to the Examiner.

Respectfully submitted,

McDERMOTT WILL & EMERY LLP



Stephen A. Becker
Registration No. 26,527

600 13th Street, N.W.
Washington, DC 20005-3096
Phone: 202.756.8000 SAB:aph
Facsimile: 202.756.8087
Date: October 3, 2005

**Please recognize our Customer No. 20277
as our correspondence address.**

INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)				ATTY. DOCKET NO. 067161-0301		SERIAL NO. Not yet assigned 10/551553	
				APPLICANT Toshihiko TANAKA			
				FILING DATE October 03, 2005		GROUP Not yet assigned	
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Code ² (if known)		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	
		US	6,128,067	10-3-2000	Hashimoto		
		US					
		US					
		US					
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		US					
		US					
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		US					
		US					
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	CITE NO.	Foreign Patent Document Country Codes -Number -Kind Codes (if known)		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Figures Appear	Translation Yes No
		JP	6-275493 /	9-30-1994	Fujitsu Ltd.		w/English Abstract
		JP	5-90128 /	4-9-1993	Nikon Corp.		w/English Abstract
		JP	6-140306 /	5-20-1994	Nikon Corp.		w/English Abstract
		JP	8-203806 /	8-9-1996	Sony Corp.		w/English Abstract
		JP	64-67914 /	3-14-1989	Hitachi, Ltd.		w/English Abstract
		JP	2000-3028 /	1-7-2000	Toshiba Corp.		w/English Abstract
		JP	3-210560	8-13-1991	Fujitsu Ltd.		w/English Abstract
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
EXAMINER'S INITIALS	CITE NO.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.					
		"Immersion Lithography Technology", NIKON Corp. retrieved February 19, 2004, via Internet					
EXAMINER				DATE CONSIDERED			

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.